

EAST Search History

EAST Search History (Prior Art)

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	5521	(438/14,18,108,763).CQLS.	USPAT; USOCR	OR	OFF	2011/03/24 20:39
L2	1057	L1 and (sputtering or ion adj milling)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2011/03/24 20:39
L3	237	L2 and (semiconductor and cleaning)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2011/03/24 20:39
L4	156	L3 and @ad< "20040225"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2011/03/24 20:39
L5	65	L4 and (argon or Ar or helium or He or neon or Ne)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2011/03/24 20:39
L6	5521	(438/14,18,108,763).CQLS.	USPAT; USOCR	OR	OFF	2011/03/24 20:40
L7	1057	L6 and (sputtering or ion adj milling)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2011/03/24 20:40
L8	237	L7 and (semiconductor and cleaning)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2011/03/24 20:40

L9	1847	(semiconductor with (wafer or substrate) with (test\$3 or prob\$3)) and ((ion milling) or (sputter\$3 with etch\$3))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2011/03/24 20:40
L10	1091	L9 and @ad< "20040225"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2011/03/24 20:40
L11	157	L10 and (((ion milling) or (sputter etch\$3)) and (testing or probing or test or probe\$1) with wafer)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2011/03/24 20:40

EAST Search History (Interference)

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3/ 24/ 2011 9:16:29 PM
**C:\Documents and Settings\bau\My Documents\EAST\Workspaces\Metallization\Electrical
 Contacts\10786807 bumps made of gold and its cleaning using ion milling before probing.wsp**